

## **Thermophysical Properties of Semiconductor Process Gases Determined with Acoustic Techniques**

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We measured the speed of sound in the process gases  $\text{Cl}_2$ ,  $\text{HBr}$ ,  $\text{BCl}_3$ ,  $\text{WF}_6$ ,  $\text{C}_2\text{H}_4\text{O}$  (ethylene oxide) and in the surrogate gases  $\text{SF}_6$ ,  $\text{CF}_4$ , and  $\text{C}_2\text{F}_6$ . (The surrogate gases are used to in the calibrate mass flow controllers.) The data span the temperature range 200 K to 475 K and the pressure range 25 kPa to 1500 kPa or to 80% of the vapor pressure for condensable gases. The data were analyzed to obtain ideal-gas heat capacities  $C_p(T)$  with uncertainties of  $0.001 \times C_p$ . The data were also used to parameterize model pair and three-body intermolecular potentials which, in turn, were used to estimate the properties of the gases up 1000 K, a temperature well above the range of the data. From the model potentials, we calculated the equation of state  $P(V,T)$  and the viscosity  $\eta(T)$ . For gases where other data exist, we find the errors in calculated properties are less than  $0.001 \times V$  and  $0.1 \times \eta$ . The thermal conductivity  $\kappa(T)$  was estimated from  $\eta(T)$  and  $C_p$  with an uncertainty of approximately  $0.1 \times \kappa$ . We plan similar measurements in other process gases and gas mixtures, direct acoustic measurements of the transport properties, and the dissemination of the results in a user-friendly data base.